[Sample holder]

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Claim

Sample holder for metal samples, which are to undergo a surface treatment on a grinding or polishing machine, with the following characteristics:

- (a) the sample holder has the shape of a circular disk;
- (b) the circular disk has recesses for mounting the metal sample to be treated;
- (c) the sample holder is detachably mountable on a rotatable shaft:

characterized by the following characteristics:

- (d) the sample holder has a number of cylindrical inserts (2);
- (e) the inserts (2) are wedged in the disk (1);
- (f) through the inserts (2), respectively, one oblong hole
 (14) passes;
- (g) at one end, around the oblong hole (14), a number of radial grooves (15) and a number of concentric grooves (16) are arranged within a sealing ring (17), projecting from the surface;
- (h) at the other end of the oblong hole (14), a vacuum connection is provided in order to tightly hold the thin metal sample (18) by means of a suction force against the grooved surface of the inserts (2).

Description

The invention relates to a sample holder for metal samples, which are to undergo a surface treatment on a grinding or polishing machine, with the following characteristics:

(a) the sample holder has the shape of a circular disk;

- (b) the circular disk has recesses for mounting the metal sample to be accommodated;
- (c) the sample holder is detachably mountable on a rotatable shaft.

Such sample holders are used in the steel industry, but also in other branches of industry, for example, in order to prepare the surface of rolled steel samples for a subsequent microscopic examination. With the presently available sample holders, the samples are fastened in the recesses, for example, with cement. Following this fastening, the sample holder is pressed against a rotating grinding or polishing disk. During the grinding of thin samples, for example, with a thickness of 0.25 mm or less, the sample may become heated due to the heat generated during the grinding process to temperatures which are above a certain limit.

This is undesirable and may lead to a false interpretation during later microscopic testing. Also, it is possible for the samples to fall out of the sample holder which leads to undesirable bending and folding which is disadvantageous as well.

It is the task of the invention to create a sample holder of the initially mentioned type to which the samples may be easily attached and removed again without being subjected to overheating.

In accordance with the invention, this task is solved by means of a sample holder with the following characteristics:

- (d) the sample holder has a number of cylindrical inserts;
- (e) the inserts are wedged into the disk;
- (f) through the inserts, respectively, one oblong hole passes;
- (g) at one end, around the oblong hole, a number of radial grooves and a number of concentric grooves are arranged within a sealing ring, projecting from the surface;

An embodiment example of the invention is shown in the drawing, wherein

Figure 1 shows a top view of a sample holder at a reduced scale;

Figure 2 shows a side view of the sample holder in accordance with Figure 1;

Figure 3 shows a view of the sample holder from below in accordance with the Figures 1 and 2;

Figure 4 shows a cross section through one of the inserts an enlarged scale;

Figure 5 shows an even more greatly enlarged cross section of the vacuum guide of the sample holder according to Figures 1 to 4.

The circular disk (1), shown in the Figures 1, 2 and 3, consists of stainless steel and is provided with six cylindrical inserts (2) made of brass. In order to be able to tightly wedge these inserts (2) into the circular disk (1), incisions (3) cut with a saw and locking screws (4) are provided.

On the upper surface of each insert (2), connection nipples (5) are arranged which are connected by means of a hose or tube connection (6) with a double nipple (7) which is part of a vacuum guide block (9), fastened onto a base plate (8). To this vacuum guide block (9), a vacuum tube (10) is connected.

The vacuum guide block (9) serves simultaneously also as a means for detachably fastening the entire sample holder to a rotatable shaft, not shown here in greater detail, of a grinding and polishing machine. For this purpose, it is provided with a snap-on head (11). At its surface, three coupling holes (12) are

provided into which extend supporting bolts of the above-mentioned machine, which are not shown here in greater detail.

The base plate (8) is fastened to the circular disk (1) by means of fixing screws (13).

Figure 4 shows an insert (2) in cross section on an enlarged scale. It has an oblong hole (14), whose upper end is provided with a connection nipple (5). On the underside, the insert (2) has, for example, four radial grooves (15) and ten concentric grooves (16). These are surrounded by a rubber sealing ring (17) which lies in a deep groove and practically completely fills it up and has, for example, a width of 1.6 mm and a depth of 3.8 mm. Figure 4 shows that a thin, disk-shaped sample (18) of rolled steel rests against the rubber sealing ring (17) with the burr originated by the punching unit.

In order to insure that the suction effect of the vacuum applied by means of the vacuum tube (10) affects the six samples (18) while the entire sample holder is being turned, an integral vacuum guide block (9) is provided, as shown on an enlarged scale in Figure 5.

With the vacuum tube (9), a barrel ring (19) is connected which, like the vacuum tube (10), is stationary. The barrel ring (19) has on one inner surface an annular groove (19A) which is connected by means of a number of radial boreholes (26) with a central borehole (27) in the lower section (9B) of the vacuum guide block (9). The central borehole (27) is closed off completely airtight at its underside by means of a plug (24). On three sides, radial boreholes (25) are connected with the double nipples (7) which are screwed on at the lower part (9b).

Furthermore, in this lower part, three blind holes (22) are provided by means of which the coupling to the base plate (8) is

effected. The upper portion (9A) of the vacuum guide block (9) is screwed together with the lower part (9B), so that the two parts can turn freely about the barrel ring (19), wherein a locking screw (23) prevents the two parts (9A, 9B) from turning independently of each other.

In the barrel ring (19), two O-rings (20) are provided which seal off both parts of the vacuum guide block (9). Furthermore, at the upper and lower surfaces of the barrel ring (19), concentric labyrinth grooves (21) are formed for the same purpose.

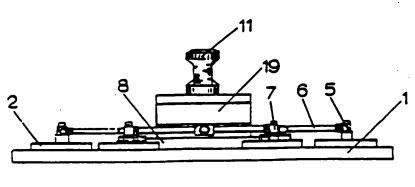
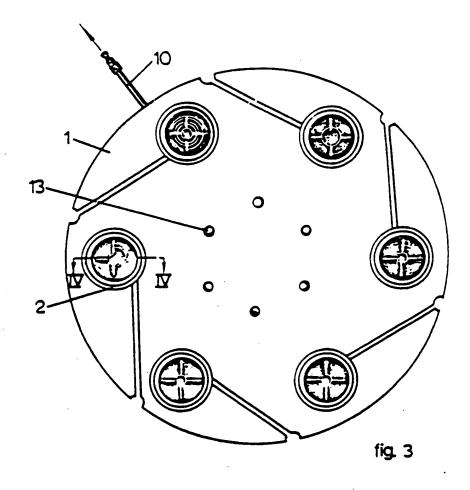
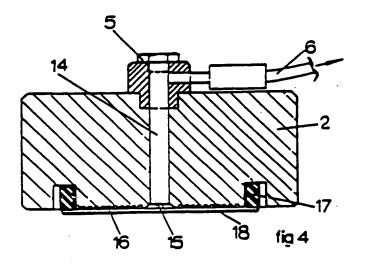


fig. 2

fig. 1





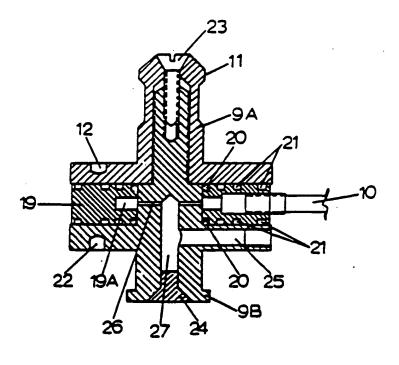


fig.5

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Rollennummer

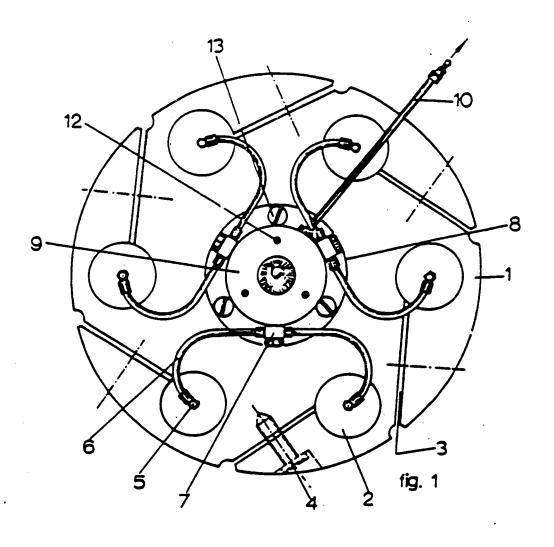
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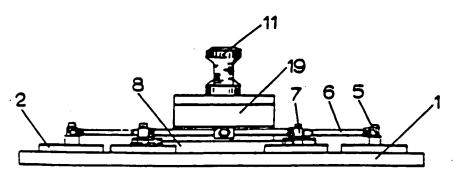


fig. 2



Anspruch:

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Probenhalter

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Probenhalter für Metallproben, die einer Oberflächenbehandlung auf einer Schleif- oder Poliermaschine zu unterziehen sind, mit folgenden Merkmalen:

- (a) der Probenhalter hat die form einer Kreisscheibe;
- (b) die Kreisscheibe hat Ausnehmungen zur Aufnahme der zu behandelnden Metallprobe;
- (c) der Probenhalter ist lösbar an einer drehbaren Welle befestigbar;

gekennzeichnet durch folgende Merkmale:

- (d) der Probenhalter hat eine Anzahl von zylindrischen Einsatzkörpern (2);
- (e) die Einsatzkörper (2) sind in der Scheibe (1) eingektemmt;
- (f) durch die Einsatzkörper (2) geht jeweils ein Längsloch (14);
- (g) an einem Ende sind um das Längsloch (14) eine Anzahl von Radialnuten (15) und eine Anzahl von konzentrischen Nuten (16) innerhalb eines von der

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Oberfläche vorstehenden Dichtrings (17) angeordnet;

(h) am anderen Ende des Längslochs (14) ist eine Vakuumverbindung vorgesehen, um die dünne Metallprobe (18) mittels Saugkraft fest gegen die genutete Oberfläche der Einsatzkörper (2) zu halten.



<u>Baschreibung:</u>

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<u>Probenhalter</u>

Die Erfindung bezieht sich auf einen Probenhalter für Metallproben, die einer Oberflächenbehandlung auf einer Schleif- oder Poliermaschine zu unterziehen sind, mit folgenden Merkmalen:

- (a) der Probenhalter hat die Form einer Kreisscheibe;
- (b) die Kreisscheibe hat Ausnehmungen zur Aufnahme der zu behandelnden Metallprobe;
- (c) der Probenhalter ist lösbar an einer drehbaren Welle befestigbar.

Solche Probenhalter werden in der Stahlindustrie, aber auch in anderen Industriezweigen benutzt, um beispielsweise die Oberfläche von gerollten Stahlproben für eine nachfolgende mikroskopische Prüfung zu präparieren. Bei den derzeit lieferbaren Probenhaltern werden die Proben in den Ausnehmungen beispielsweise mit Zement befestigt. Nach dieser Befestigung wird der Probenhalter gegen eine rotierende Schleif- oder Polierscheibe gepreßt. Beim Schleifen von dünnen Proben, beispielsweise mit einer Dicke von 0,25 mm oder weniger, kann sich die Probe aufgrund der bei dem Schleifvorgang entstehengen Hitze auf Temperaturen erwärmen, die oberhalb einer bestimmten Grenze liegt. Dies ist unerwünscht und kann zu einer falschen Interpretation bei

der späteren Mikroskopprüfung führen. Auch können die Proben aus dem Probenhalter herausfallen, was zu unerwünschten Verbiegungen und Faltungen führt, was ebenfalls nachteilig ist.

Der Erfindung liegt die Aufgabe zugrunde, einen Probenhalter der eingangs genannten Art zu schaffen, an dem die Proben leicht befestigt und wieder entfernt werden können und keiner Überhitzung unterliegen.

Diese Aufgabe wird erfindungsgemäß durch einen Probenhalter mit folgenden Merkmalen gelöst:

- (d) der Probenhalter hat eine Anzähl von zylindrischen Einsatzkörpern;
- (e) die Einsatzkörper sind in der Scheibe eingeklemmt;
- (f) durch die Einsatzkörper geht jeweils ein Längsloch;
- (g) an einem Ende sind um das Längsloch eine Anzahl von Radialnuten und eine Anzahl von konzentrischen Nuten innerhalb eines von der Oberfläche vorstehenden Dichtrings angeordnet;
- (h) am anderen Ende des Längslochs ist eine Vakuumverbindung vorgesehen, um die dünne Metallprobe mittels Saugkraft fest gegen die genutete Oberfläche der Einsatzkörper zu halten.

Ein Ausführungsbeispiel der Erfindung ist in der Zeichnung dargestellt. Es zeigen:

Figur (1) eine Draufsicht auf einen Probenhalter in

verkleinertem Maßstab;

- figur (2) eine Seitenansicht des Probenhalters gemäß
 figur (1);
- Figur (3) eine Ansicht des Probenhalters gemäß den Figuren (1) und (2) von unten;
- Figur (4) einen Querschnitt durch einen der Einsatzkörper in vergrößertem Maßstab;
- figur (5) einen noch weiter vergrößerten Querschnitt der Vakuumführung des Probenhalters nach den figuren (1) bis (4).

Die in den figuren (1), (2) und (3) dargestellte Kreisscheibe (1) besteht aus rostfreiem Stahl und ist mit sechs zylindrischen Einsatzkörpern (2) aus Messing versehen. Um diese Einsatzkörper (2) in der Kreisscheibe (1) festklemmen zu können, sind eingesägte Einschnitte (3) und Klemmschrauben (4) vorgesehen.

Auf der Oberseite jedes Einsatzkörpers (2) sind Verbindungsnippel (5) angeordnet, die über eine Schlauchoder Rohrverbindung (6) mit einem Doppelnippel (7) verbunden sind, das Teil eines auf einer Grundplatte (3) befestigten Vakuumführungsblocks (9) ist. An diesem Vakuumführungsblock (9) ist ein Vakuumrohr (10) befestigt.

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Der Vakuumführungsblock (9) dient gleichzeitig auch als lösbare Befestigung des gesamten Probenhalters an einer hier nicht näher dargestellten drehbaren Welle einer Schleif- und Poliermaschine. Hierfür ist er mit einem

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Schnappverschlußkopf (11) ausgestattet. An seiner Oberfläche sind drei Kupplungslöcher (12) vorgesehen, in die hinein sich hier nicht näher dargestellte Trägerbolzen der vorgenannten Maschine erstrecken.

Die Grundplatte (8) ist an der Kreisscheibe (1) mittels Fixierschrauben (13) befestigt.

figur (4) zeigt einen der Einsatzkörper (2) in einem Querschnitt in vergrößertem Maßstab. Er weist ein Längsloch (14) auf, dessen oberes Ende mit einem Verbindungsnippel (5) versehen ist. Auf der Unterseite weist der Einsatzkörper (2) beispielsweise vier Radialnuten (15) und zehn konzentrische Nuten (16) auf. Diese werden von einem Gummidichtring (17) umgeben, der in einer tiefen Nut liegt und diese praktisch vollständig ausfüllt und dabei beispielsweise eine Breite von 1,6 mm und eine Tiefe von 3,8 mm hat. Figur (4) zeigt, daß eine dünne, scheibenförmige Probe (18) aus Walzstahl am Gummidichtring (17) mit dem durch das Stanzen entstandenen Grat anliegt.

Damit gesichert ist, daß der Saugeffekt des über das Vakuumrohr (10) aufgeprägten Vakuums auf die sechs Proben (18) wirkt, während der gesamte Probenhalter gedreht wird, ist ein integraler Vakuumführungsblock (9) vorgesehen, wie er in vergrößertem Maßstab in Figur (5) dargestellt ist.

Mit dem Vakuumrohr (9) ist ein Laufring (19) verbunden, der ebenso wie das Vakuumrohr (10) stationär ist. Der Laufring (19) hat an einer Innenseite eine Ringnut (19A), die über eine Anzahl von Radialbohrungen (26) mit einer Zentralbohrung (27) im unteren Teil (9B) des

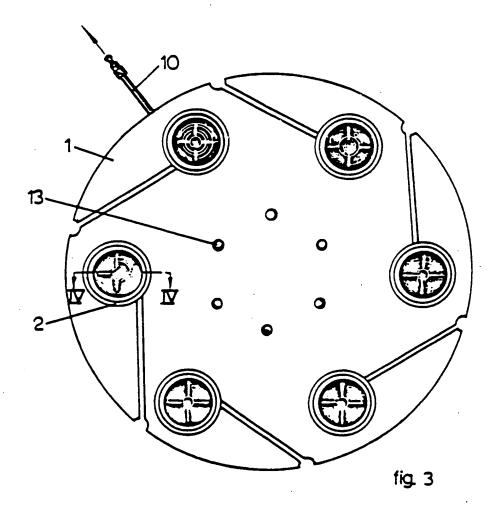


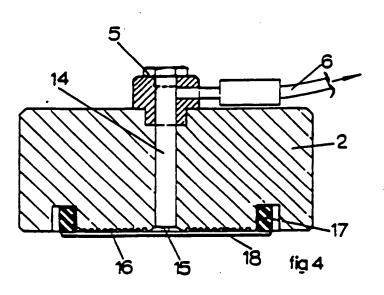
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Vakuumführungsbiocks (9) verbunden ist. Die Zentralbohrung (27) ist vollständig luftdicht an ihrer Unterseite durch einen Stopfen (24) verschlossen. Auf drei Seiten sind Radialbohrungen (25) mit den Doppelnippeln (7) verbunden, die am unteren Teil (9b) angeschraubt sind.

In diesem unteren Teil sind des weiteren drei Blindlöcher (22) vorgesehen, durch die das Kuppeln zur Grundplatte (8) bewirkt wird. Der obere Teil (9A) des Vakuumführungsblocks (9) ist mit dem unteren Teil (9B) verschraubt, so daß die beiden Teile frei um den Laufring (19) drehen können, wobei eine Sicherungsschraube (23) verhindert, daß sich die beiden Teile (9A, 9B) unabhängig voneinander verdrehen.

Im Laufring (19) sind zwei O-Ringe (20) vorgesehen, die beide Teile des Vakuumführungsblocks (9) abdichten. ferner sind an den Ober- und Unterflächen des Laufring (19) konzentrische Labyrinthnuten (21) für den gleichen Zweck eingeformt.





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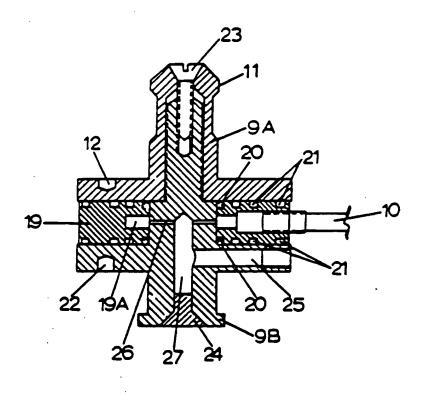


fig.5

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WORKPIECE HOLDING MECHANISM FOR A PLANE POLISHING DEVICE

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[There are no amendments to this patent.]

Claim

1. A workpiece holding mechanism for a plane polishing device characterized in that it contains a holding part, which holds a workpiece that is on top of the polishing surface of the plane polishing device and is equipped with a convex spherical surface centering around one point on the surface of the said workpiece to be processed; a support part, which is provided for maintaining a constant orientation and is equipped with a concave spherical surface, which engages with the aforementioned convex spherical surface in a freely oscillating manner centering about one point on the aforementioned workpiece; and a flexible body, which is provided between the aforementioned holding part and the aforementioned supporting part and has high torsional rigidity but can bend freely.

Detailed explanation of the invention

Industrial application field

The present invention concerns a workpiece holding mechanism for a plane polishing device. In particular, it concerns a holding mechanism for a workpiece in a plane polishing device which polishes the surface of thin plates.

Prior art

Generally, a workpiece holding mechanism for a plane polishing device is constructed to include a holding area, where the workpiece is held on top of a polishing surface of the plane polishing device, and the surface of the workpiece is polished by oscillating [vibrating while moving] the workpiece over the polishing surface.

Figure 2 is a longitudinal section of a workpiece holding mechanism for a plane polishing device of the prior art. In Figure 2, a disk (1) of the plane polishing device is rotated about a shaft (2). Also, a sleeve (4) is attached to a frame (3) of the plane polishing device in a freely rotatable manner, and a splined shaft (5) is attached to the central hole of this sleeve (4) in a freely movable manner in the direction of the shaft and in such a manner that it rotates together with the sleeve (4) about the shaft. A lever (7), which is attached to an air cylinder (6) provided for the frame (3), engages with the splined shaft (5) in a freely rotatable manner. Also, a gear (9), which is attached to a motor (8) provided for the frame (3), engages with a gear (10), which is provided at the sleeve (4).

A hemispherical body (11) engages with the curved area in the form of a spherical surface that is provided at the front end of the splined shaft (5) in a freely oscillating manner. A pressing plate (12) is fixed to the hemispherical body (11), and a frame (13) is provided at the pressing plate (12). A pin (14), which is provided at the frame (13), engages with a groove (15), which is provided at the front end of the splined shaft (5). A compression spring (16), which is provided between the splined shaft (5) and the frame (13), interacts to press the hemispherical body (11) onto the splined shaft (5) in order to prevent the hemispherical body (11) from falling when the splined shaft (5) ascends.

A through-hole (17), which is provided at the pressing plate (12), and a through-hole (18), which is provided between the hemispherical body (11) and the pressing plate (12), are connected to a vacuum pump (not shown) through a pipe (19), which passes through a hole provided at the splined shaft (31), in order to vacuum hold material (20), which is a magnetic disk forming the workpiece, onto the pressing plate (12). A ring (21) is also provided and fixed at the pressing plate (12) in order to determine the position of the material (20).

To polish the surface of the material (20) with this plane polishing device, the air cylinder (6) is actuated so that the pressing plate (12) ascends and so that the material (20) is vacuum held against the inner side of the ring (21) at the lower surface of the pressing plate (12). Next, the pressing plate (12) is lowered by the air cylinder (6) through rotation of the motor (8), and the material (20) is pressed against the polishing surface (22) of the disk (1). Also, a polishing solution (not shown) is spread over the polishing surface (22). Accordingly,

the bottom surface of the material (20) is polished by the action of its own rotations and vibrations by the rotation of the disk (1).

The polishing surface (22) of the disk (1) is processed to have a flat surface; however, a small amount of waviness remains in many actual cases. Accordingly, it is necessary for the material (20) and the pressing plate (12) to be able to tilt slightly along the waviness of the polishing surface (22) in order for the material (20) constantly to adhere close to the polishing surface (22) for a smooth finish. This tilting is obtained when the hemispherical body (11) vibrates with the spherical concave area of the splined shaft (5). Moreover, the material (20) tilts while centering around the center C because the center C of the spherical surface of the nemispherical body (11) is established to be positioned at the bottom surface of the material (20), and the position of the bottom surface of the material (20) does not change even though it is tilted, and polishing can occur.

The pipe (19) is elastic and can absorb some tilting in the hemispherical body (11). Also, the hemispherical body (11) vibrates around the splined shaft (5); therefore, it is designed so that the rotation by the motor (8) is transmitted to the pressing plate (12) and the material (20) when the pin (14) engages with the groove (15).

Problems to be solved by the invention

However, the ability of the pressing plate (12) and material (20) to follow the waviness of the polishing surface (22) was not satisfactory. One factor is the generation of a large amount of

friction between the pin (14) and the groove (15). Figure 3 is a schematic diagram explaining the force that is applied to the pin (14), and it corresponds to the right side surface diagram of the major part in Figure 2. In Figure 3, force b, which is equal to the friction between the material (20) and the polishing surface (22), is applied to the groove (15) from the pin (14) when the splined shaft (5) rotates, as illustrated by arrow a. Furthermore, since a condition is created, in which the right side opens between the material (20) and the polishing surface (22), as illustrated in Figure 1, by the waviness of the polishing surface (22), and if force P is obtained by the piston (6), force P interacts upwards at the left edge of the material (20). To consider the equilibrium of the moment about center C, where the length between center C of the spherical surface of the hemispherical body (11) and the left edge of the material (20) is d and the height between center C and the pin (14) is h, a force of Pd/h is also applied to the pin (14). In practice, this force P becomes considerably large; therefore, a large force also acts on the pin (14), resulting in a large frictional force.

There was also the problem of the pin (14) being constantly pressed toward the left by the groove (15) in Figure 3, causing the pressing plate (12) to swing around the pin (14) according to the waviness of the polishing surface (22), the base ([illegible]) of the pin (14) to change its position to the left or the right relative to the splined shaft (5), and a fluctuation to occur in the rotation of the pressing plate (12).

The aim of the present invention is to offer a workpiece holding mechanism for a plane polishing device in which the aforementioned problems are solved, there is a satisfactory following of the waviness of the polishing surface by tilting of

the workpiece, and the fluctuation in the rotation of the workpiece is reduced for a smooth polishing of the workpiece.

Means to solve the problems

The present invention comprises a holding part (34), which holds the workpiece that is on top of the polishing surface of the plane polishing device and is equipped with a convex spherical surface centering around one point on the surface of the said workpiece to be processed; a support part (32), which is provided for maintaining a constant orientation and is equipped with a concave spherical surface, which engages with the aforementioned convex spherical face in a freely vibrating manner centering about one point on the aforementioned workpiece; and a flexible body (36), which is provided between the aforementioned holding part (34) and the aforementioned support part (32) and has high torsion rigidity but can bend freely.

Function

The elastic body (36), which has torsional rigidity but can bend freely, tilts the holding part (34) against the support part (32) while following the waviness of the polishing surface and not generating a large amount of friction. During this process, the holding part (34) does not separate from the support part (32) in the direction of rotation.

Next, an application example of the present invention will be explained with reference to a figure. Figure 3 [sic; 1] is a longitudinal section of an application example of the present invention. A disk (1), shaft (2), frame (3), sleeve (4), air cylinder (6), lever (7), motor (8), and gears (9) and (10) are the same as those illustrated in Figure 1 [sic; 2]. A splined shaft (31) is attached to the sleeve (4) so that it can freely oscillate in the direction of the shaft and rotate together with it around the shaft. A hemispherical body (33) engages with the concave part in the form of a spherical surface, which is provided at a flange (32) at the lower end of the splined shaft (31) in a freely oscillating manner. A pressing plate (34) is fixed to the hemispherical body (33). A through-hole (35) of the pressing plate (34) is connected to a pipe (19) in order to hold the material (20) against the pressing plate (34).

The upper end of bellows (36) is fixed to the flange (32) and its lower end to the pressing plate (34). The torsional rigidity of the bellows (36) with respect to the central shaft is high, but it can expand and bend in the direction of the central shaft; therefore, the pressing plate (34) does not separate from the flange (32) in the direction of rotation, but it can tilt freely. Accordingly, a large frictional force is not generated even when the pressing plate (34) is tilted, and the pressing plate (12) and the material (20) satisfactorily follow the waviness of the polishing surface.

The present invention can also be applied to plane polishing devices, in which the disk is fixed, and the pressing plate (34),

for example, rotates together with the frame (3) around the shaft (12).

A steel ball, for example, may also be included between the concave spherical surface of the supporting part and the convex spherical surface of the holding part so that the friction can be reduced.

Furthermore, the elastic body that is provided between the support part and the holding part does not necessarily have the form of a bellows. For example, dividing the bellows in the circumferential direction, in other words, several plate springs that are bent in the middle and arranged over the circumference may also be used.

Effect of the invention

As explained above, in the workpiece holding mechanism for a plane polishing device of the present invention, the holding part is tilted without the generation of a large amount of friction between the groove and the pin by using an elastic body which has torsional rigidity but which can expand and bend freely, instead of an engagement between the groove and the pin, and the workpiece can satisfactorily tilt with and follow the waviness of the polishing surface.

Also, oscillations around the pin are eliminated when the support part is tilted, a fluctuation in the rotating speed of the workpiece can be made very small, and the effect is smooth polishing of the workpiece.

Brief description of the figures

Figure 1 is a longitudinal section of an application example of the present invention. Figure 2 is a longitudinal section of an example of a workpiece holding mechanism for a plane polishing device of the prior art. Figure 3 is a model diagram which explains the force which interacts on the pin (14) as an example illustrated in Figure 2.

1...disk, 5, 31...splined shaft, 11, 33...hemispherical body, 12, 34...pressing plate, 14...pin, 15...groove, 20...material, and 36...bellows.

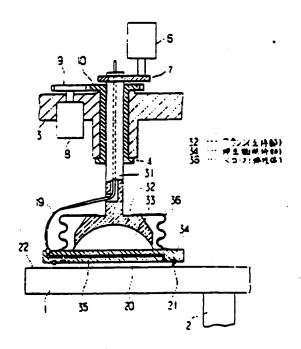


Figure 1

Key: 32

Flange (supporting part)
Pressing plate (holding part)
Bellows (elastic body) 34

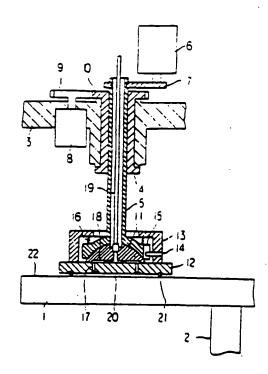


Figure 2

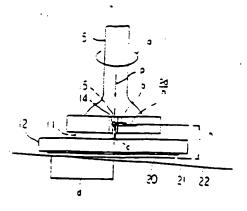


Figure 3

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APPLICATION DATE

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INVENTOR : KAMATA TAKEMI; others: 01

: B24B37/04; B24B7/16; INT.CL.

B24B41/06

: WORK HOLDING MECHANISM FOR TITLE

SURFACE POLISHING MACHINE

22 20

・・・フランジを中心)

: PURPOSE: To polish a work smoothly by providing a resilient ABSTRACT bellows between the work holding section having convex face and the supporting member having concave face engagable slidably with

the convex face.

CONSTITUTION: Semi-spherical body 33 secured to a pressboard 34 i engaged slidably with spherical recess made in the lower end flange 32 of spline shaft 31 to adsorb a material 20 through a hole 35 communicated with a tube 19 to the pressboard 34. A bellows 36 having high rigidity in the rotary direction while flexible against the vertical shrinkage and bending is secured between said flange 32 and the pressboard 34. Consequently, the work 20 or the pressboard 34 will follow the waving of the polishing face 22 well to reduce the fluctuation of the rotary speed of the work 20 thus to polish the work 20 smoothly.

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8308-3C 零差請求 未請求 発明の数 l (全4頁)

9発明の名称 平面研算装置の復加工物保持接続

②神 ■ 昭59-145408

母出 第 昭59(1984)7月13日

東京都港区芝5丁目33番1号 日本電気株式会社内 東京都港区芝5丁目33番1号 日本電気株式会社内

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13代 理 人 弁理士 管 野 中

.....

子面保護機能の被除工物保持機能

1.等许指求の概要

(1) 平面教育機関の発酵を出り、他加工物を使用しての根加工物の被加工部上の一点を中心とする。 及其を有する場所等と、各种を一定に借つて設け られ時間を用工物上の一点を中心とし変配の政策 に理論を使に係合する凹級類を有する工作等と、 時に供料器と前記工作器の間に設けられまりに対 して以前性が大きくせがに対してはる次を単位に とを有することを特定とする平面教育品度の普及 では、

1 E S O P 4 1 P 8

: 48 ± 0 88 66

・ 年発明は、 子通研修協会の 後 元万智信を指令。 時代 可吸の 突然を研修するための 子差値線接合の 要加工物機や機能が加える。

.....

--

語を含んで表現され、表現間上にかいてはなり、 を理論をせて等格工物の表面を避過している。 第2 間は、従来の子原原要は既のは在工物の保存 受用の問題はつるる。まで現代を知られて平ちられる。 一方子原展理器既のファーム3にはマットでもの 選集を完まり付われ、このキリーでものがり ですりている。マレームの代表である。 だけられている。マレームはではなっていた。 によっている。マレームのではなけられたエファー に対けられている。マレームはではスプァール はずりになかり付けられたいパーではスプァール はずりになかり付けられたいパーではスプァール はずりになかり付けられたいパーではスプァール はずりになかり付けられたののではスプァール はまりになからになっている。またいパール におけた自転10と世界をかつている。

アプライン機会の毛海疾器と大学を大力・新に 手能体11 が機能力な疾患をしている。それは11 に 単圧機能が引きまれ、単圧機能的は、中はがなけ られている。他は内臓がられたビン16性、エブラ イン機会の無磁性を対象を15 に含むしている。

計算句 51: 25758(2)

スファイン 個 5 と無けの間に受けられた主要はね 16 は 単独仏(1 をスプライン個 5 に 押し付けるよう で作用し、スリーで幅 5 が上半したと変化単数体 (1 が 毎下するのを防止してべる。

伊生県は代牧けられた場合礼17をジェはな11と 伊田県12の間に設けられた場合礼18は、スプライン報31に設けた大を辿る者18を介して異なインプ (黒京省略)に連絡され、彼や工物である観気が スプの集存的を理生成12に異立義者するためたも のである。また業存20の位置を決めるために伊田 (仮12ペリンブ11が複数されている。

この平面研算機能でまれかの発達を研修するには、エフィリングを作曲をマで存圧機能を上昇させ、まれかを存圧機能の下型のリング社の内質に再登録者である。 反にュータをにより関係をでながら存圧機能をエアンリングをにより下降をでまれかを明書 1 の研修園はには、研修機能が数率をはている。 使つて無対的の下面は、自からの機能にいる。使つて無対的の下面は、自からの機能をの開催 1 の機能による機能で研究を作る。

円含1の課金数なな、平面にちゃったででごされているが変形には値がであるからなったが発表れている場合が多う。まつてまれ20を研究者22では でいる場合が多う。まつてまれ20を研究者22では だ思着されて持ちかに研修するには、まれわな少 作生後はを研修第22でのうなりを使つて多り値とと とができるようにすると優がある。この場合は、 手様体11のメノファン側5の様々の当場との情報 で得られ、しかも手様体11の最本の中してがまれ かの下面に生きするように設定されているのでま け20位中にでを中してして傾き、傾いても実行か の下面の生態な変化をする時度することができる。

なか習得に保性を有しませな11の多少の場合は 表現できる。また単数は11がエブティン語を応行 し掲載するため、ピン14と前15の協会により押圧 優は及び素質的までモータをによる複数が扱わる ようにしている。

(希腊が用来しょうとする問題点)

しかし、月生度はそび意味20の資産を22のうれ りに行する過程性はあまりよくなかつた。このま 知の一つはエン14と第15の間に大きな意識力が生

また、無り見だかいてでいるはありだより方式 行為を式得されることとなり前標をはのりなりで 使つて严圧感になせいはを中心として最り動わせ もこととなり、エアティン物を式打して移行的式 でいるの項をトロな存在式位し、严圧をはの影響 に変勢が充じることとなるというでもかめつた。 本発明の目的は、上記欠点を取るし、被加工物の組まの研制値のうわりに対する過程性がよく、 また表面工物の関係変勢を少くして円骨に被加工 物を供収することが可能な手機の単級変数の関加工

物理特殊者を提供することにある。 (簡素点を解決するための手段)

本義領は、子の研究自動の研想を上の被称工物を保持しての確如工物の被加工場上の一点を中心とするのが他を有する保持機器と、保持を一定に扱って設けられる配質加工物上の一点を中心とし現記のは最に明確の正式を分する必然のを有するのである。

75 AT

れじりにさいては無性を与り合呼におしては表 めた単性は18は少年が3分を支持等はにおりが必要 のうなりに温度をせててきた原理りを生じること 立く、順動をでる。その環境時間34は支持器以に

##461- 25798 (3)

りし直転方用だなずれない。

(FRE)

次に本意明の実践例について協盟を自用して投 明する。第3 選は本義明の一貫機例の提訴事態で ある。円書1、他を、フレーム3、スリーアも、 エアノリンドも、レバーで、キーテキ、他最も10 以第1 選に示すものと同じである。エプライン機 11 は、他方向には機能を定に機能のうには一体と なつて退転するようにスリーフもに取り付けられ ている。エグライン機11 の下機のフランノ11 に設 けた発表状の凹層に手球体13 が理能を定に係をし ている。平常は21に存在後34が環境をたている。 件圧振34の場合孔35は管理と基礎をれます20を停 圧振34に依身するためのものである。

べっ一次雑割上間をフランジはに環境して目を 界圧遅れに開発して設けられている。ペーーが雑 は中心知識のりのおじりに対しては耐性が大多い のに対し、中心部方向の用機及び自びに対しては 表表であるため、存圧収みはフランジはに対しま をであるため、存圧収みはフランジはに対しま でもち、はつて戸生産36が増くときも人を生せる 力は生じて存在板は火が乗れなの研磨金のりおり ボガナら連載性はよい。

まいの意味は、円金が固定してもつてッシュム まさとも水戸圧を34年が毎12を中心として製品で もような子医療単純素のも過剰できる。

また王内部の出来者と保存的の当年者の別に無 年等を介圧をせて、母親力を減少をせることもで まる。

そうだ工作器と連伸器との間に設ける個性はは、 ビアンもベロードの単数をしていると見ばない。 例えばベロードを重要方向に分割したもの、含い 見えれば平断を考慮をせた重数の低ばれを内容上 によべたものでもよい。

(異様の効果)

本発明の平原原産製産の被加工物値特殊的は、 以上規則したように成と ピンの係合の代わりにな じりには関係を有し特殊及び合けに対して名を住 のある保住体をで引することのよう。 おと ピンと の間の大きな単細力を発生することを(分析法

が現ま、研察器のうなりに対する最初工物の組ま の過程性をよくすること的できる。

1 た機構器が減くときにピンを中心として活動 することがをくなり被加工物の機能温度の変動を 非常に小さくすることができ、内層に関加工物を 研修できる効果がある。

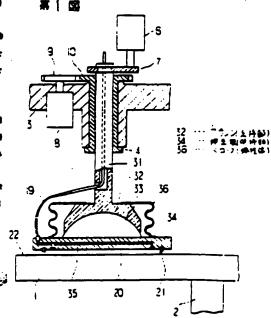
4.間番の管準を装置

第1番は本色等の一質的例の総計器等、至1番 は平面研究を見りを地工物質特殊器の変更の一例 の電景を含まるである。 に作用する力を説明するための相応望である。

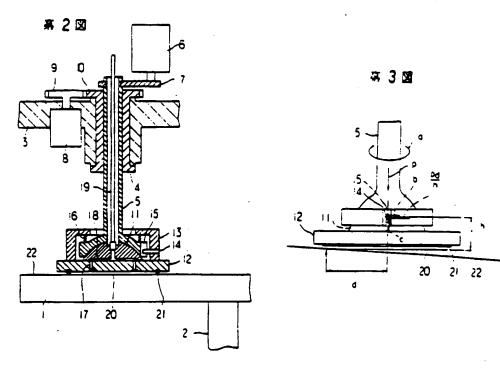
1 月費、5.31 スプライン機、31.33 中間 体、12.34 序圧症、14 ピン、15 者、20 集 材、14・ベローズ。

等野市最大 日本电讯表式合注

지원사 기원 학 중



HR961- 25758(4)



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